



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yong-Pil Han et al. Group Art Unit: 1763
Serial No.: 09/498,303 Examiner: T. Dang
Filed: February 4, 2000
For: HF VAPOR PHASE WAFER CLEANING AND OXIDE ETCHING

Box AF
THE ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, DC 20231

I hereby certify under 37 CFR 1.8(a)
that this correspondence is being
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AMENDMENT UNDER 37 C.F.R. §1.116 AFTER FINAL REJECTION

This is in reply to the Examiner's Action mailed October 7, 2002.

A petition for a three-month extension of the statutory period for reply
accompanies this response.

Amendments:

In the claims:

Please cancel claims 1-11.

Please cancel claims 22-24.

REMARKS

The Applicants gratefully acknowledge the Examiner's allowance of
claims 12-21. Claims 1-11 and 22-24 remain rejected. Claims 1-11 and 22-24
are hereby canceled to put the application in condition for allowance.